

## ABSTRACT

A microhole-formed stretched porous  
polytetrafluoroethylene material, in which a microhole  
5 having a hole diameter greater than an average pore  
diameter of a stretched porous polytetrafluoroethylene  
material is formed in the stretched porous  
polytetrafluoroethylene material by irradiation of a pulse  
laser beam having a pulse length of at most 10 picoseconds,  
10 and the microporous structure of the wall surface of the  
microhole is substantially retained without being destroyed,  
a production process thereof, and an abrasion working  
process.